P27374.A07.doc Application No. 10/605,108

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Dureseti CHIDAMBARRAO, et al.

Group Art Unit: 2814

Appln. No. : 10/605,108

Examiner: PHAM, Long

Filed

: September 9, 2003

Confirmation No. 2107

For

: METHOD FOR REDUCED N+ DIFFUSION IN STRAINED SI

ON SI/GE SUBSTRATE

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents U.S. Patent and Trademark Office Customer Service Window, Mail Stop Amendment Randolph Building 401 Dulany Street Alexandria, VA 22314 Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56, and supplemental to the Information Disclosure Statement filed on August 25, 2005, applicant respectfully brings the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application.

Further to the U.S. Patent and Trademark Office's decision to waive the requirement under 37 C.F.R. § 1.98 (a)(2)(i), copies of the U.S. patents and U.S. published patent applications are not enclosed herewith. However, if any copies are needed, the Examiner is respectfully requested to contact the undersigned. Copies of non-US patent documents as well as the documents listed in the "Other Documents" section of the attached PTO-1449 are enclosed.

Applicants respectfully request that the Examiner consider the materials cited and indicate such consideration by appropriately initialing the enclosed PTO-1449 Form and including a copy of the initialed form in the next official communication.

Applicants note that this Information Disclosure Statement is being after receipt of a first action on the merits from the U.S. Patent and Trademark Office. Accordingly, please charge the required fee of \$180.00 to IBM Deposit Account No. 09-0458 (Fishkill).

Should the US Patent & Trademark Office conclude that other fees are required, authorization is hereby given to charge **IBM Deposit Account No. 09-0458** (Fishkill) any fee necessary to ensure consideration of these materials.

Should there be any questions concerning this application, the Examiner is invited to contact the undersigned at the below listed telephone number.

Respectfully submitted, Dureseti CHIDAMBARRAO, et al.

Andrew M. Calderon Reg. No. 38,093

May 15, 2006 GREENBLUM & BERNSTEIN, P.L.C. 1950 Roland Clarke Place Reston, VA 20191 (703) 716-1191

FORM PTO-1449		partment of Co t and Trademar									
INFOR		Applicant Dureseti CHIDAMBARRAO, et al.									
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<sup>\*</sup>EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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